

PTO-1449 Information Disclosure Citation In an Application		Application No. <b>10/649,925</b>	Applicant(s) <b>Kovacevic et al.</b>	
		Docket Number <b>021791.0109</b>	Group Art Unit <b>2125</b>	Filing Date <b>08/25/2003</b>

*MAR 14 2005*  
U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
CK	A 6,122,564	09/19/2000	Koch et al.	700	123	06/30/1998
CK	B 6,188,041	02/13/2001	Kim et al.	219	121.63	11/13/1998
CK	C 6,311,099	10/30/2001	Jasper et al.	700	166	10/15/1998
CK	D 6,401,001	06/04/2002	Jang et al.	700	118	07/22/1999
CK	E 6,459,951	10/01/2002	Griffith L.	700	166	09/10/1999
CK	F 6,526,327	02/25/2003	Kar et al.	700	119	12/07/2000
CK	G 6,638,787	10/28/2003	Buchin et al.	438	75	12/04/2001
CK	H US 2004/0107019	06/03/2004	Keshavmurthy et al.	700	118	07/18/2003
I						
J						
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L						
M						
N						

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES      NO
CK	O	07/06/1999	Japan	B23K	26/02	XX
CK	P WO 03/070414 A1	08/28/2003	PCT	B23K	26/03	XX
Q						

## OTHER DOCUMENTS (Including Author, Title, Source, and Pertinent Pages)

DATE

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S	
T	

## EXAMINER

*Chuck Karay*

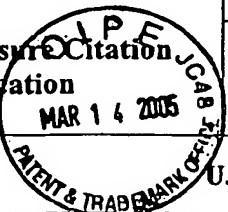
## DATE CONSIDERED

*3/28/05*

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

U.S. PATENT AND TRADEMARK OFFICE

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		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
CK	A	6,391,251	05/21/02	Keicher et al.	419	7	05/09/2000
CK	B	6,580,959	06/17/2003	Mazumder	700	121	05/19/2000
	C						

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	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
CK	D						

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
CK	E B. Grünenwald et al., "New Technological Developments in Laser Cladding", Proceedings of the International Congress on Applications of Lasers and Electro-Optics (ICALEO 1993), pp. 934-944.	1993
CK	F Lii et al., "Sensing, Modelling and Closed Loop Control of Powder Feeder for Laser Surface Modification", Proceeding of the International Congress on Applications of Lasers and Electro-Optics (ICALEO 1993), pp. 965-974.	1993
CK	G F. Meriaudeau et al., "Acquisition and Image Processing System Able to Optimize Laser Cladding Process", From the Proceeding of ICSP '96, Laboratoire GERE - Université de Bourgogne, France, pp. 1628-1631.	1996
CK	H William H. Hofmeister et al., "Video Monitoring and Control of the Lens Process", Proceedings of AWS 9th International Conference on Computer Technology in Welding, 1998, pp. 187-196	1998
CK	I Ivan S. Knecko et al., "Influence of Geometrical Factor on Heat Transfer Rate During GTAW for Welding-Based Deposition", Proceedings of Free Symposium on Nontraditional Manufacturing Research and Applications, the 2001 International Mechanical Engineering Conference, Nov. 11-16, 2001, New York, N.Y., (9 pages)	2001
CK	J D. Hu et al., "Improving Solid Freeform Fabrication by Laser-Based Additive Manufacturing", Research Center for Advanced Manufacturing, Southern Methodist University, Richardson, Texas, USA, © ImechE, 2002, Proc. Instn Mech. Engrs Vol. 216 Pat B: J. Engineering Manufacturing, pp. 1253-1264.	2002
CK	K D. Hu et al., "Modelling and Measuring the Thermal Behavior of the Molten Pool in Closed Loop Controlled Laser-Based Additive Manufacturing", Research Center for Advanced Manufacturing, Southern Methodist University, © ImechE, 2003, Proc. Instn Mech. Engrs Vol. 217 Pat B: J. Engineering Manufacturing (12 pages)	2003
CK	L Dongming Hu et al., "Sensing, Modeling and Control for Laser-Based Additive Manufacture", International Journal of Machine Tools & Manufacture 43 (2003) pp. 51-60	2003
CK	M	

EXAMINER <i>Chris Kovacevic</i>	DATE CONSIDERED <i>3/28/05</i>
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